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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

RYUJI BIRO, ET AL.

Application No.: 10/098,569

Filed: March 18, 2002

For: VACUUM DEPOSITION  
SYSTEM AND THIN-FILM  
DEPOSITION PROCESS

Examiner: Richard R. Bueker

Group Art Unit: 1763

# 7A  
516103  
mw

April 21, 2003

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Commissioner for Patents  
Washington, D.C. 20231

AMENDMENT

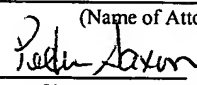
Sir:

a) Introductory Comments

This Amendment is filed in accordance with the OG.Notice -1267 Off. Gaz.  
Pat.Office 106 of February 25, 2003 - in which 37 C.F.R. §1.121(a)-(d) is waived for  
amendments to the application where the Amendment complies with the Revised  
Amendment Format of the OG Notice.

In response to the outstanding restriction requirement, kindly amend the  
subject application as follows:

I hereby certify that this correspondence is being deposited with the  
United States Postal Service as first-class mail in an envelope addressed  
to: Commissioner for Patents, Washington, D.C. 20231 on  
April 21, 2003  
(Date of Deposit)

PETER SAXON (24947)  
(Name of Attorney for Applicant)  
 April 21, 2003  
Signature Date of Signature